Please amend the Abstract as follows:

This invention relates to a process for manufacturing an anisotropic conducting film

comprising a layer of electrically insulating material and conducting through inserts, the said

process comprising including the following steps: a) formation on a substrate of at least one

layer of material with through holes, the said layer being called the perforated layer, b) filling

of the through holes to form conducting inserts. The process also comprises includes

production of a mask partially covering a first end of the conducting inserts and etching of the

unmasked part of the ends of the conducting inserts so as to obtain conducting inserts with

pointed ends. The invention is applicable to the formation of components (chips, integrated

circuits) with a high interconnections density.

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2